

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of: **OZAKI, Takashi, et al.**

Group Art Unit: **1792**

Serial No.: **10/528,137**

Examiner: **MACARTHUR, Sylvia**

Filed: **December 12, 2005**

P.T.O. Confirmation No.: **2307**

**FOR: SUBSTRATE PROCESSING APPARATUS AND METHOD FOR  
MANUFACTURING A SEMICONDUCTOR DEVICE**

**RESPONSE UNDER 37 CFR §1.116**  
**- EXPEDITED RESPONSE -**  
**GROUP ART UNIT 1792**

**MAILSTOP AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

February 4, 2010

Sir:

In response to the Final Office Action dated **November 13, 2009**, please amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 12 of this paper.